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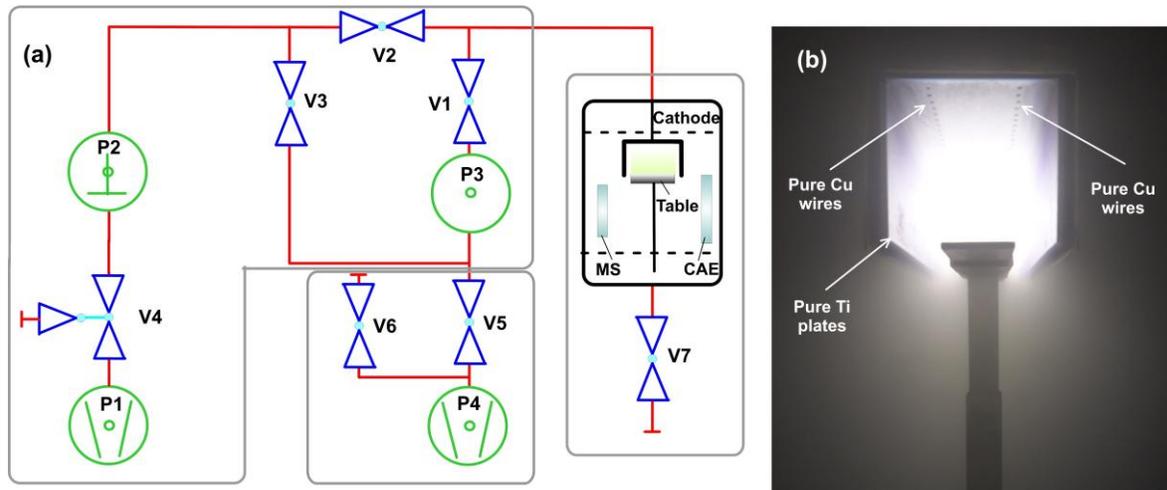


NATIONAL  
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# PVD Coatings Deposition

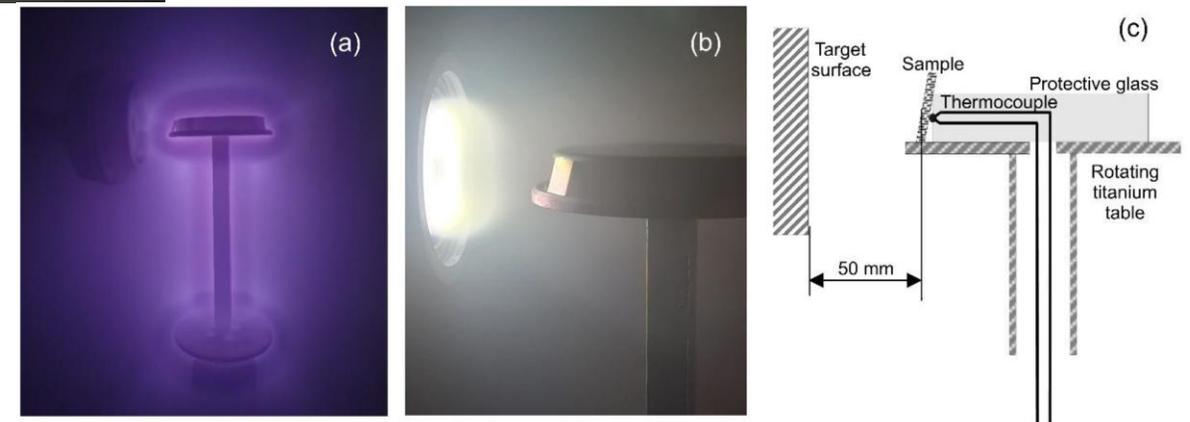
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# PVD Techniques for Thin Film Deposition

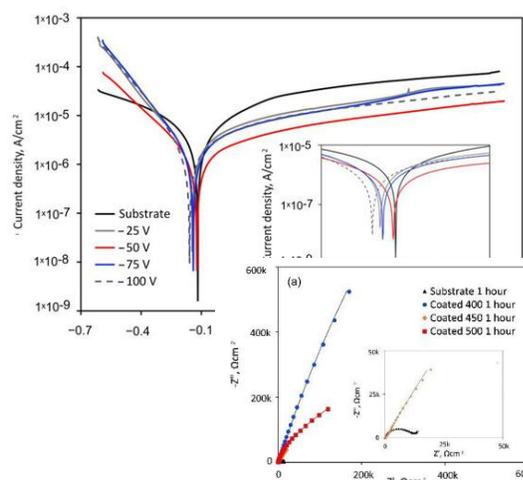
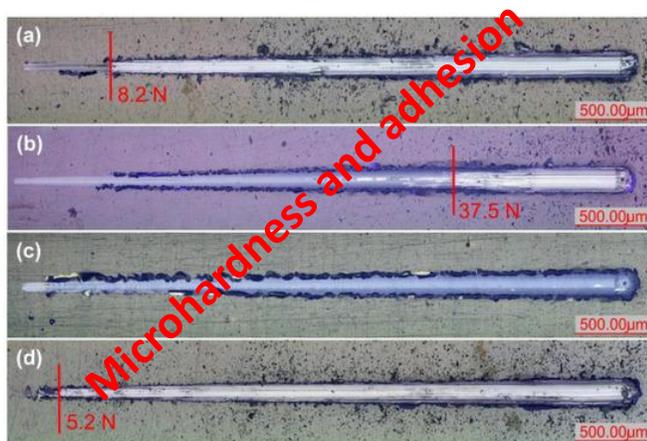
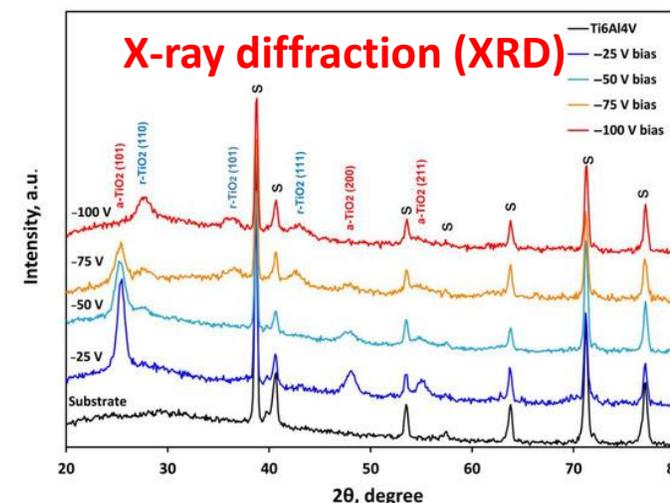
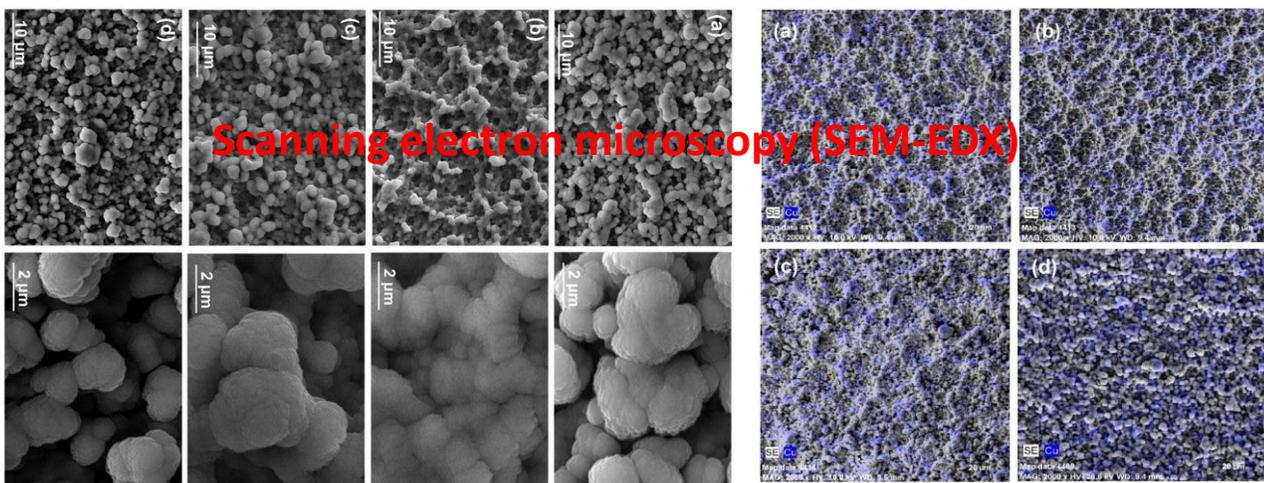


**Figure 1.** A schematic diagram of the installation (a) with its vacuum pumping system: P1 and P4 – fore vacuum roughing pump, P2 - booster-type bi-rotor vacuum roughing pump, P3 – diffusion pump, V1÷V7 – vacuum valves (gate valves); (b) photograph of the working glow-discharge system

**Figure 2.** Images of the glow-discharge cleaning (a) DC magnetron sputtering of an oxide coating from Ti-Cu target (b) and a schematic view of the experimental setup with a thermocouple sensor (c).



# Thin Films' Characterization



## Electrochemical tests

